



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Mutsumi KIMURA et al.

Application No.: 10/764,502

Filed: January 27, 2004

Docket No.: 118215

For: THIN FILM TRANSISTOR TYPE DISPLAY DEVICE, METHOD OF
MANUFACTURING THIN FILM ELEMENT, THIN FILM TRANSISTOR CIRCUIT
BOARD, ELECTRO-OPTICAL DEVICE, AND ELECTRONIC APPARATUS

SECOND INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
2. Relevance of the references is discussed in the present specification.

Respectfully submitted,

James A. Oliff
Registration No. 27,075

Eric D. Morehouse
Registration No. 38,565

JAO:EDM/gam

Date: February 17, 2004

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

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| Form PTO-1449 (REV. 8-83) | | US Dept. of Commerce PATENT & TRADEMARK OFFICE | ATTY DOCKET NO. 118215 | APPLICATION NO. 10/764,502 | | |
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| INFORMATION DISCLOSURE STATEMENT <i>O I P E</i> <i>FEB 17 2004</i> <i>JCT174</i> <i>PATENT OFFICE</i> | | (Use several sheets if necessary) | | | | |
| | | APPLICANT(S) Mutsumi KIMURA et al. | | | | |
| | | FILING DATE January 27, 2004 | GROUP | | | |
| U.S. PATENT DOCUMENTS | | | | | | |
| EXAMINER INITIAL | | DOCUMENT NUMBER | DATE | NAME | CLASS | SUB CLASS |
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| FOREIGN PATENT DOCUMENTS | | | | | | |
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| OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.) | | | | | | |
| 1 | SHIMODA et al., "Surface Free Technology by Laser Annealing (SUFTLA)", <i>IEEE</i> , 1999, pp. 289-292. | | | | | |
| 2 | UTSUNOMIYA et al., "Low Temperature Poly-Si TFTs on Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA™)", <i>SID 00 DIGEST</i> , 2000, pp. 916-919. | | | | | |
| 3 | SHIMODA, "Future Trend of TFTs", <i>Asia Display/IDW '01</i> , pp. 327-330. | | | | | |
| 4 | UTSUNOMIYA et al., "Low Temperature Poly-Si TFT-LCD Transferred onto Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA®)", <i>Asia Display/IDW '01</i> , pp. 339-342. | | | | | |
| 5 | SHIMODA, "Future Trend of TFT Technology", <i>AM-LCD '02</i> , pp. 5-8. | | | | | |
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| EXAMINER | | | | DATE CONSIDERED | | |
| Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | | | | | | |